SUPERCRITICAL CPD MEMS DRYER FOR 4" WAFERS
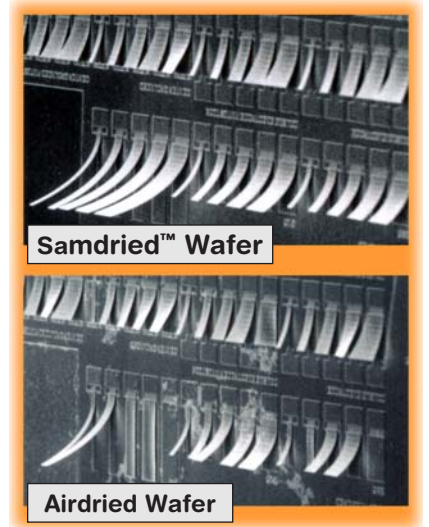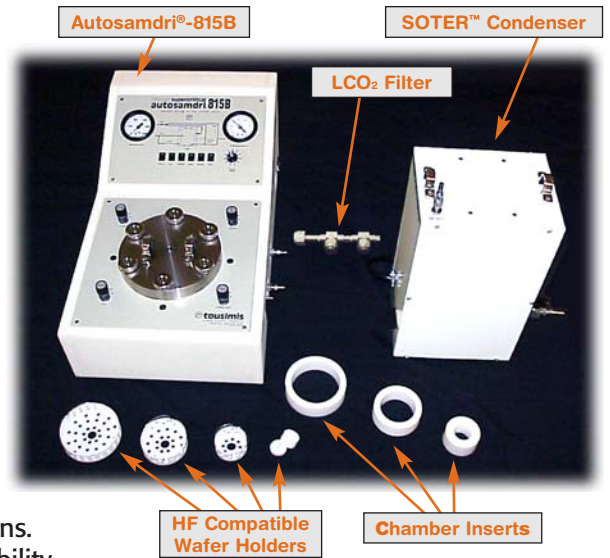# AUTOSAMDRI®-815B, SERIES B

- The Supercritical **Autosamdri®-815B, Series B** System was developed by Dr. A.J. Tousimis and our team of long-standing associates within the tousimis® SAMDRI design group.

- Smooth operation and precise control are the Supercritical **Autosamdri®-815B**'s trademark; wafer holders and inserts are provided that allow anti-stiction processing up to 5 pieces of either 4", 3", 2" wafers or 10mm square die per process run!

®tousimis

SUPERCRITICAL Autosamdri®-815B, Series B
Catalog# 8780C *(Process Various Wafer Sizes up to 4in)*

Autosamdri®-815B · SOTER™ Condenser · LCO₂ Filter · HF Compatible Wafer Holders · Chamber Inserts

FEATURES

- Microprocessor controller allows for complete automatic processing.*
- All internal surfaces are inert to CO_2 and ultrapure alcohols.*
- Repeatable operating parameters insuring reproducibility of results.*
- Integrated temperature controls.*
- Internal rupture disc built in for safety. *
- Processes up to 5 x 4" diam. wafers per run; comes with additional HF compatible wafer holders to process 5 x 3", 5 x 2" diameter wafers or 5 x 10mm square die (tousimis® HF compatible Wafer Holders* can be used to transport and process your wafers and die from HF).
- All electronic components meet CE, UL and/or U.S. Military Specifications.
- Static pressure control module pre-set for automatic safe pressure stability.
- 0.08µm internal filtration system delivers clean filtered LCO_2 to process chamber. *
- Under-lit chamber with viewing window facilitates operator chamber status viewing.
- An efficient adiabatic cooling system*, capable of cooling the chamber from ambient room temperature to near 0°C, in less than 3 minutes and maintains temperature automatically during both FILL and PURGE modes.*
- LED's instantly indicate process mode at a glance.*
- Clean room static-free compatible design.
- For added safety and convenience, the U.S. Patented SOTER™ condenser* quietly captures exhaust and alcohols.
- Unique chamber inserts* allow variance of chamber I.D. This maximizes efficiency in LCO_2 consumption and processing time.
- On-site Start-up and User(s) Training by a qualified tousimis® technician included.[1]

Samdried™ Wafer

Airdried Wafer

SPECIFICATIONS

- Cabinet: 14.25" (36.2cm) Width x 11.75" (29.8cm) Height x 25" (63.5cm) Length
- System Set-Up Area Required: 42" (107cm) Width x 30" (76cm) Depth
- Chamber size: 4.50" I.D. x 1.25" depth Chamber volume: 326 ml
- Temperature gauge range: -30°C to 60°C, Pressure gauge range: 0 to 2,000psi
- 120V/50-60Hz (Other voltage units also available. Please Inquire)
- LCO_2 flow is controlled through Micro Metering Valves with Vernier handles for easily controlled flow rates.*

STANDARD ACCESSORIES

- LCO_2 High Pressure braided stainless steel inert Teflon® lined hose. 10ft (~ 3m) long for clean room operation (at a nominal charge, other lengths available upon request).
- Double T-Filter Assembly (#8785) pre-installed onto the chamber LCO_2 supply high-pressure hose. Flows LCO_2 twice thru 0.5 µm filters with 99.5% particulate retention prior to LCO_2 entering Autosamdri®-815B.
- New SOTER™ Condenser* connects to exhaust hose. Captures all alcohol and deadens exhaust noise.*
- Static free Exhaust Tubing for all exhaust outlets.
- Internal stainless and nickel scintered filtration systems incorporated to protect lines, wafers, and valves down to 0.4µm.
- Spare Chamber O-ring (3), Chamber Lamps (2), and 5A Slo-Blow Fuses (2).
- 3 Chamber Inserts.* Enables original chamber ID reduction down to smaller chamber ID sizes for a range including: 4", 3", 2", and 1.25" !
- 4", 3", 2" diameter Wafer Holders and 10mm square Die Holder included. Holders are HF compatible and can hold up to 5 wafers or die each.
- Free lifetime technical support consultation by our scientific staff.
- 2 year warranty on all parts and labor.